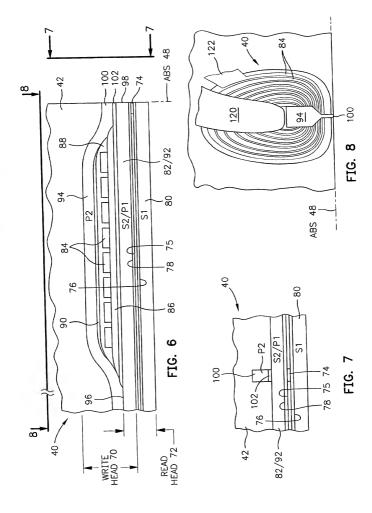


FIG. 5



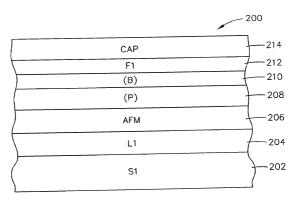


FIG. 9

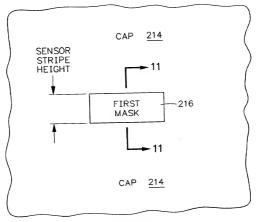
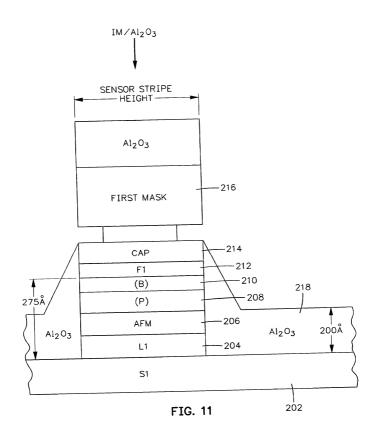
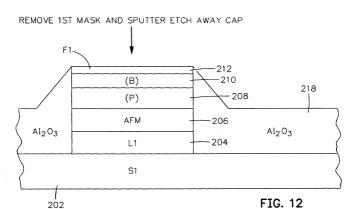


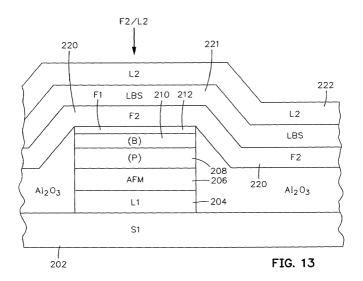
FIG. 10



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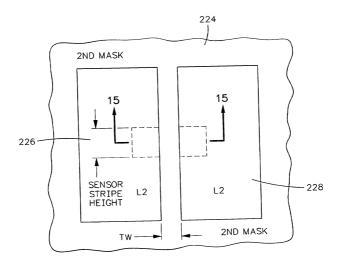


FIG. 14

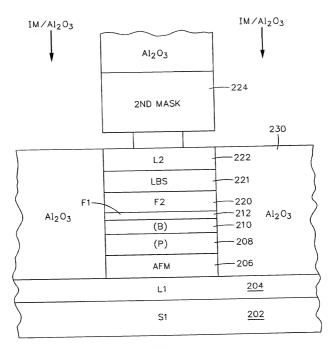
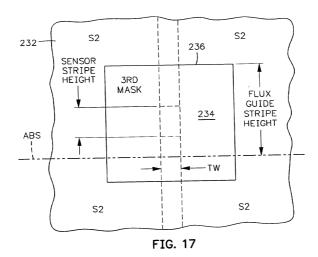


FIG. 15

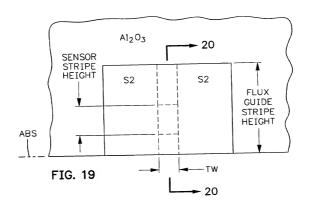
REMOVE 2ND MASK DEPOSIT S2

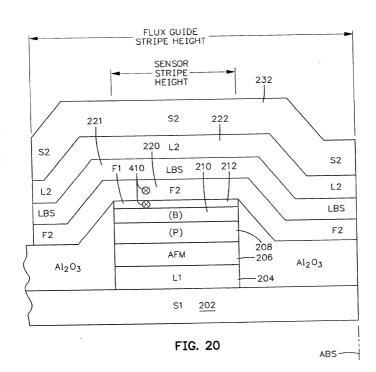
FIG. 16

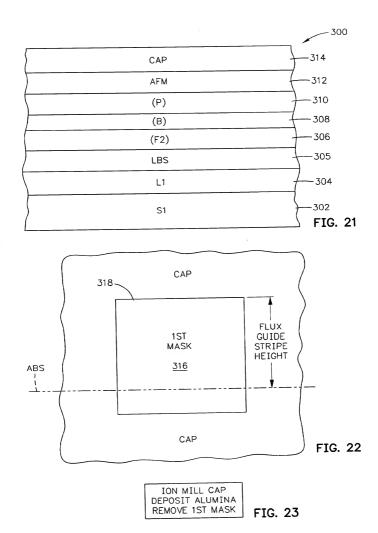
ı

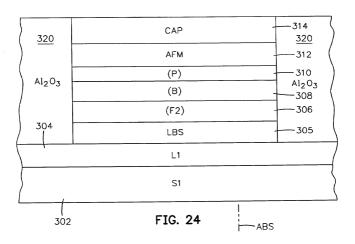


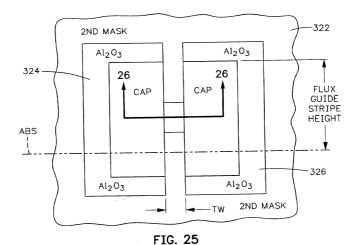
ION MILL
REMOVE 3RD MASK
FIG. 18

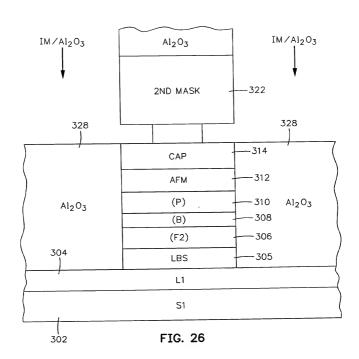












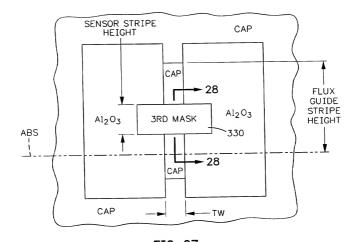
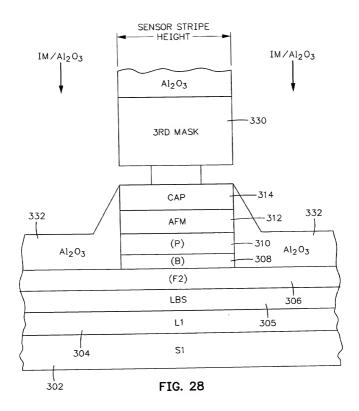
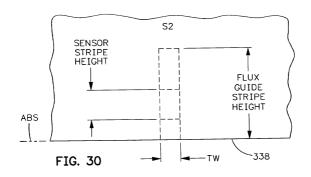


FIG. 27



REMOVE 3RD MASK DEPOSIT L2/S2

FIG. 29



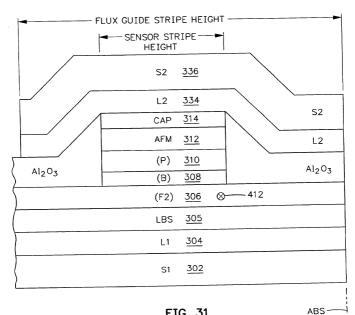


FIG. 31

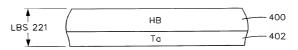


FIG. 32

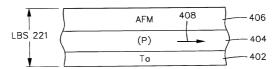


FIG. 33

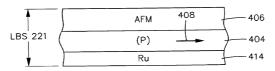


FIG. 34